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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **OZAKI, Takashi, et al.**

Group Art Unit: 1763

Serial No.: **10/528,137**

Examiner: **Sylvia MacArthur**

Filed: **December 12, 2005**

P.T.O. Confirmation No.: 2307

FOR: **SUBSTRATE PROCESSING APPARATUS AND METHOD FOR
MANUFACTURING A SEMICONDUCTOR DEVICE**

REQUEST FOR STATUS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Date: July 13, 2006

Sir:

The undersigned attorney requests the status of the above-identified application.

The application was filed on **December 12, 2005**, in the U.S. Patent and Trademark
Office and to date no Office Action has been received.

In the event any fees are required in connection with this paper, please charge Deposit
Account No. 01-2340.

Respectfully submitted,

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